

PATENT
8007-1118

IN THE U.S. PATENT AND TRADEMARK OFFICE

In re application of

Masaru HOSOKAWA et al. Conf. 4713

Application No. 10/594,567 Group 1793

Filed September 27, 2006 Examiner S. Abu Ali

MATERIAL FOR CHEMICAL VAPOR DEPOSITION
AND THIN FILM FORMING METHOD

AMENDMENT

Assistant Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

November 28, 2008

Sir:

In response to the Official Action mailed August 28, 2008, please amend the above-identified application as follows:

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this paper.

Remarks begin on page 6 of this paper.